



PATENT
ATTORNEY DOCKET NO. 46884-5446

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Kenshi FUKUMITSU)
)
U.S. Application No.: 10/564,840) Confirmation No.: 3420
)
Filed: January 17, 2006) Examiner: Unassigned
)
For: LASER BEAM MACHINING METHOD,)
LASER BEAM MACHINING APPARATUS,)
AND LASER BEAM MACHINING PRODUCT)
(As Amended))

Commissioner of Patents
U.S. Patent and Trademark Office
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Alexandria, VA 22314

Sir:

INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. § 1.97(b)

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), Applicants bring to the attention of the Examiner the documents listed on the attached PTO-1449. This Information Disclosure Statement is being filed before the mailing date of a first Office Action on the merits for the above-referenced application.

An International Search Report (ISR) dated November 2, 2004 is attached together with a copy of each document listed on the PTO Form 1449 that is not a U.S. patent or U.S. patent publication.

Applicants respectfully request that the Examiner consider the listed documents and evidence that consideration by making appropriate notations on the attached form. As for any document listed on the accompanying PTO-1449 that is in a language other than English,

relevance can be understood from an enclosed English abstract or at least partial translation or from mention in the specification or in a search report for a corresponding application.

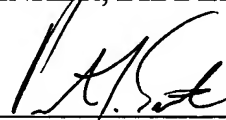
This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that the listed documents are material or constitute "prior art." If it should be determined that any of the listed documents do not constitute "prior art" under United States law, Applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such document.

Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over any of the listed documents, should any of the documents be applied against the claims of the present application.

Except for issue fees payable under 37 C.F.R. § 1.18, the Commissioner is hereby authorized by this paper to charge any additional fees during the entire pendency of this Application, including fees due under 37 C.F.R. § 1.16 and 1.17 which may be required and including any required extension of time fees, *or* credit any overpayment to Deposit Account No. 50-0573. This paragraph is intended to be a **CONSTRUCTIVE PETITION FOR EXTENSION OF TIME** in accordance with 37 C.F.R. § 1.136(a)(3).

Respectfully submitted,

DRINKER, BIDDLE & REATH LLP

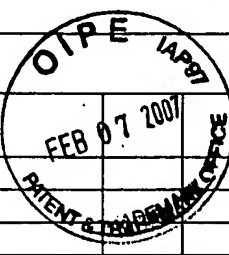


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Dated: February 7, 2007

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INFORMATION DISCLOSURE CITATION				Attorney Docket No.: 46884-5446		Serial No.: 10/564,840	
(Use several sheets if necessary)				Applicants Kenshi FUKUMITSU		Page 1 of 2	
PTO Form 1449				Filing Date: January 17, 2006		Confirmation No.: 3420	
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